

In re application of

Confirmation No. 9191

Makoto AKIZUKI et al.

Docket No. 2001-1897

Serial No. 10/025,899

Group Art Unit 1762

Filed December 26, 2001

Examiner Bernard D. Pianalto

AECEIVEL AUG 29 2003 TC 1700

METHOD FOR FORMING GAS CLUSTER AND METHOD FOR FORMING THIN FILM

PETITION FOR EXTENSION OF TIME

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of February 27, 2003.

The fee of \$930.00 is

- (X) submitted herewith.
- () to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
- () Small entity status of this application is established by a Small Entity Status Assertion which
 - () is enclosed.
 - () has been previously submitted.

Respectfully submitted,

Makoto AKIZUKI et al.

Вÿ

Matthew Jacob Registration No.25, 154

Attorney for Applicants

MJ/krl

Washington, D.C. 20006-1021 Telephone (202) 721-8200 Facsimile (202) 721-8250 August 27, 2003